

AndrĀjs E VladĀjs

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/6617790/publications.pdf>

Version: 2024-02-01

15
papers

564
citations

933447

10
h-index

996975

15
g-index

15
all docs

15
docs citations

15
times ranked

587
citing authors

#	ARTICLE	IF	CITATIONS
1	Detecting nanoscale contamination in semiconductor fabrication using through-focus scanning optical microscopy. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2020, 38, 050602.	1.2	4
2	Metrology for the next generation of semiconductor devices. <i>Nature Electronics</i> , 2018, 1, 532-547.	26.0	249
3	Research Update: Electron beam-based metrology after CMOS. <i>APL Materials</i> , 2018, 6, .	5.1	4
4	Three-Dimensional (3D) Nanometrology Based on Scanning Electron Microscope (SEM) Stereophotogrammetry. <i>Microscopy and Microanalysis</i> , 2017, 23, 967-977.	0.4	13
5	Contour metrology using critical dimension atomic force microscopy. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2016, 15, 044006.	0.9	4
6	Virtual rough samples to test 3D nanometer-scale scanning electron microscopy stereo photogrammetry. <i>Proceedings of SPIE</i> , 2016, 9778, .	0.8	5
7	A method to determine the number of nanoparticles in a cluster using conventional optical microscopes. <i>Applied Physics Letters</i> , 2015, 107, .	3.3	11
8	Optimizing hybrid metrology: rigorous implementation of Bayesian and combined regression. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2015, 14, 044001.	0.9	9
9	Scanning electron microscope measurement of width and shape of 10 nm patterned lines using a JMONSEL-modeled library. <i>Ultramicroscopy</i> , 2015, 154, 15-28.	1.9	83
10	New insights into subsurface imaging of carbon nanotubes in polymer composites via scanning electron microscopy. <i>Nanotechnology</i> , 2015, 26, 085703.	2.6	15
11	10nm three-dimensional CD-SEM metrology. <i>Proceedings of SPIE</i> , 2014, , .	0.8	12
12	Real-Time Scanning Charged-Particle Microscope Image Composition with Correction of Drift. <i>Microscopy and Microanalysis</i> , 2011, 17, 302-308.	0.4	24
13	Helium ion microscopy and its application to nanotechnology and nanometrology. <i>Scanning</i> , 2008, 30, 457-462.	1.5	43
14	Contamination specification for dimensional metrology SEMs. <i>Proceedings of SPIE</i> , 2008, , .	0.8	19
15	Scanning electron microscope dimensional metrology using a model-based library. <i>Surface and Interface Analysis</i> , 2005, 37, 951-958.	1.8	69